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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Mail Stop: ISSUE FEE**
Shoriki NARITA et al. : **Confirmation No. 1853**
Serial No. 10/019,700 : [Group Art Unit 2825
Filed January 2, 2002 : Examiner Igwe U. Anya]

BUMP FORMING APPARATUS FOR
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, CHARGE REMOVAL METHOD
FOR CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, CHARGE REMOVING UNIT FOR
CHARGE APPEARANCE SEMICONDUCTOR
SUBSTRATE, AND CHARGE APPEARANCE
SEMICONDUCTOR SUBSTRATE

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

SUBMISSION OF REFERENCES

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

Applicants request that the references listed below be placed in the file of the above-identified application:

USP 6,198,616, 03/2001, Dahimene et al.
JP 01077111, 03/1989 (Abstract)
JP 2002009569, 01/2001 (Abstract)
JP 2002203995, 07/2002 (Abstract)

Respectfully submitted,

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